

Figure 1 SOI feature etched using no pulsing (prior art)

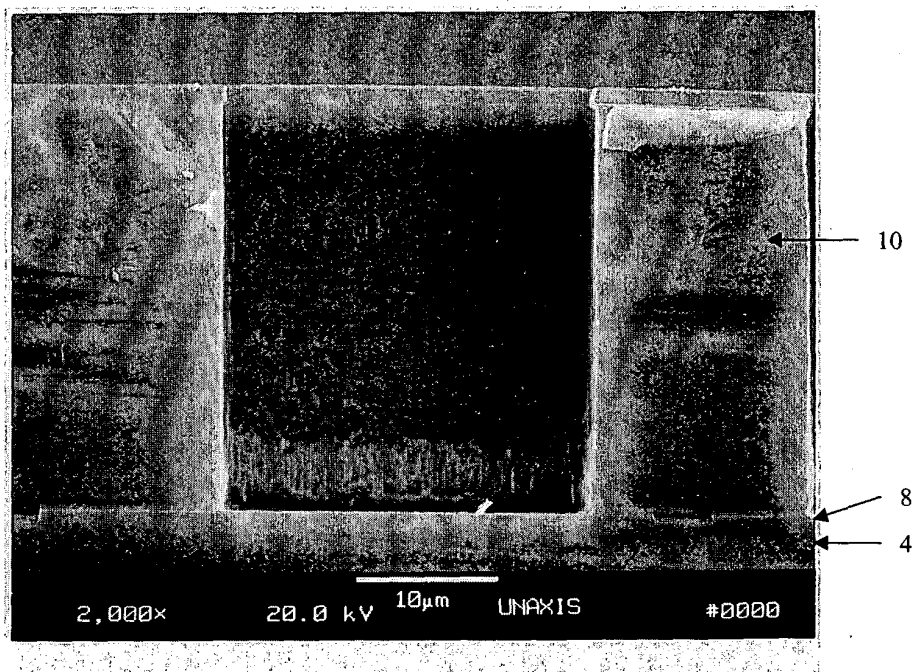


Figure 2 Same feature as Fig 1, using ICP pulsing

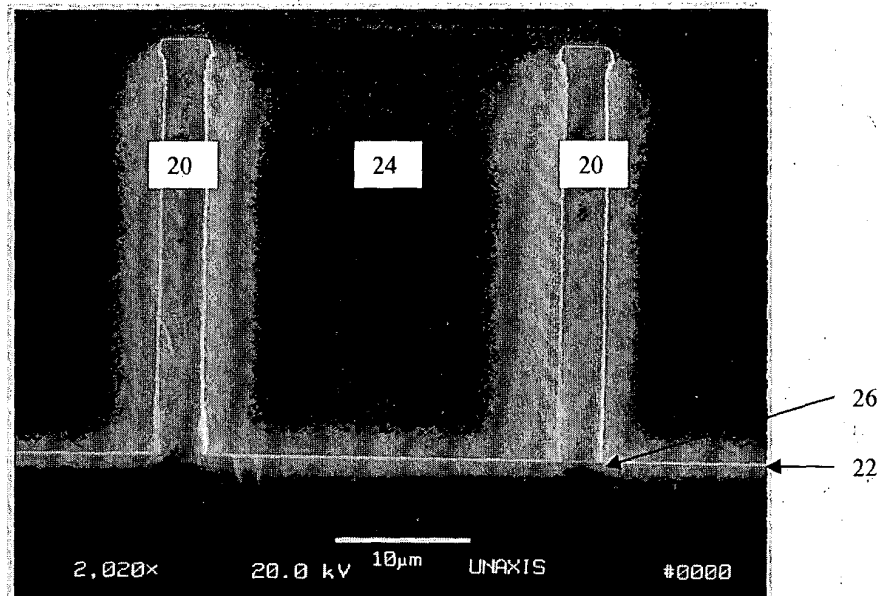


Figure 3 Narrow features etched in an SOI structure using ICP pulsing

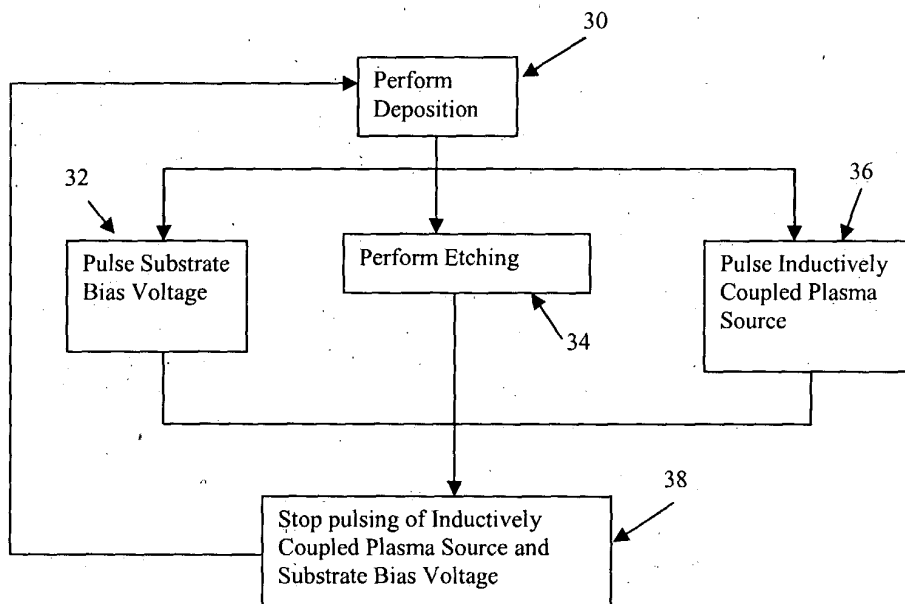


Fig. 4